

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

**In re U.S. Patent Application of** )  
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**TAI et al.** )  
 )  
**Application Number: To be Assigned** )  
 )  
**Filed: Concurrently Herewith** )  
 )  
**For: IMAGE DISPLAY DEVICE** )  
 )  
**ATTORNEY DOCKET NO. NITT.0188** )

**Honorable Assistant Commissioner  
for Patents  
Washington, D.C. 20231**

**INFORMATION DISCLOSURE STATEMENT**

Sir:

Pursuant to 37 C.F.R. §§ 1.56 and 1.97, this Information Disclosure Statement is submitted in the above-identified patent application. A listing of documents to be published on the face of any patent granted from this application is submitted herewith on Form PTO-1449. Any other documents or information submitted for consideration by the Examiner are listed in this paper. A copy of each U.S. and foreign patent, or each publication or portion thereof listed or herein identified, submitted herewith.

This Information Disclosure Statement is submitted with the initial filing of the application. Accordingly, no fee is due or payable at this time.

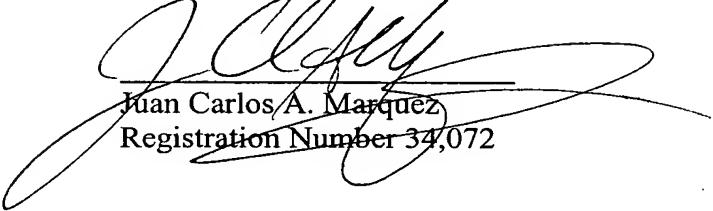
The Examiner is requested to acknowledge consideration of the information provided in this paper in accordance with prescribed procedures.

Please charge any additional fees or credit any overpayments in connection with this paper to Deposit Account No. 08-1480.

Respectfully submitted,

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U.S. Department of Commerce Patent and Trademark Office	APPLICANT TAI et al.	
Information Disclosure Statement by Applicant	FILING DATE Concurrently Herewith	GROUP

## U.S. Patent Documents

## Foreign Patent Documents

**Other Documents (Including Author, Title, Date Pertinent Pages, Etc.)**

		James B. Boyce et al., "Laser Crystallization for Polycrystalline Silicon Device Applications", Technology and Applications of Amorphous Silicon, R.A. Street ed. (2000), pp. 95-146
		Akito Hara et al., "High Performance Poly-Si-TFTs on a Glass by a Stable Scanning CW Laser Lateral Crystallization", International Electron Devices Meeting (2001), pp. 747-750
		Mutsuko Hatano et al., "12.4L: Late News Paper: Selectively Enlarging Laser Crystallization Technology for High and Uniform Performance Poly-Si TFTs", SID 02 DIGEST (2002) pp. 158-161

**EXAMINER** \_\_\_\_\_ **DATE CONSIDERED** \_\_\_\_\_

*EXAMINER: Initial if citation is considered, whether or not citation is in conformance with MPEP 609; draw a line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant*